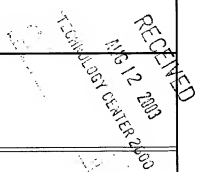


3/8/03 41 2829

AMENDMENT TRANSMITTAL LETTER (Large Entity)		Docket No. 02008/071001	
Applicant(s): Masahiro ISHIDA et al.			
Serial No. 09/980,891	Filing Date 12/03/2001	Examiner T. NGUYEN	Group Art Unit 2829



Invention: **METHOD AND APPARATUS FOR DEFECT ANALYSIS OF SEMICONDUCTOR INTEGRATED CIRCUIT**

TO THE COMMISSIONER FOR PATENTS:

Transmitted herewith is an amendment in the above-identified application.
The fee has been calculated and is transmitted as shown below.

CLAIMS AS AMENDED					
	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	21 -	31 =	0 x	\$18.00	\$0.00
INDEP. CLAIMS	3 -	5 =	0 x	\$84.00	\$0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00

- ☒ No additional fee is required for amendment.
- ☐ Please charge Deposit Account No. _____ in the amount of _____
- ☐ A check in the amount of _____ to cover the filing fee is enclosed.
- ☒ The Director is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account No. **50-0591**
 - ☒ Any additional filing fees required under 37 C.F.R. 1.16.
 - ☒ Any patent application processing fees under 37 CFR 1.17.

Jonathan P. Osha 48,885
Signature

Dated: 8/6/2003

Jonathan P. Osha, Reg. No. 33,986
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I certify that this document and fee is being deposited on _____ with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.
Signature of Person Mailing Correspondence
Typed or Printed Name of Person Mailing Correspondence

CC:



ATTORNEY DOCKET NO.: 02008/071001; AD-0243PCTUS

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masahiro ISHIDA *et al.*

Art Unit : 2829

Serial No.: 09/980,891

Examiner : T. NGUYEN

Filed : December 3, 2001

Title : METHOD AND APPARATUS FOR DEFECT ANALYSIS OF
SEMICONDUCTOR INTEGRATED CIRCUIT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY UNDER 37 CFR § 1.111

In response to the Office Action dated May 8, 2003, please amend the application as follows and consider the included remarks.

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